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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Date: May 29, 2003

atent Application of:

Shunpei YAMAZAKI ) Group Art Unit: 2814

Serial No. 09 620,968 ) Examiner: Nathan W. Ha

Filed: July 20, 2000 ) Confirmation No. 4214

For: METHOD OF FORMING INSULATING FILMS,

CAPACITANCES, AND SEMICONDUCTOR

DEVICES

## RESPONSE TO RESTRICTION REQUIREMENT/AMENDMENT

Mail Stop Non-Fee Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In response to the Request for Restriction mailed April 29, 2003, please amend the above identified application as follows.

## IN THE CLAIMS:

Please delete claim 1 without prejudice of disclaimer to file a divisional application directed thereto.

## REMARKS

Applicants hereby elect without traverse Group II (claims 2-22), drawn to a method of making a semiconductor device, classified in class 438, subclass 123.

Consideration and allowance of the instant application are now respectfully requested.

Respectfully submitted.

Jeffer L. Costellia

Registration No. 35,483

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